#### engineering laboratory



**Engineering** Laboratory

# Proposed Standardized Test Artifact for Additive Manufacturing

Shawn Moylan, Ph.D. NIST Intelligent Systems Division shawn.moylan@nist.gov

> PDES, Inc. Workshop March 14, 2013



#### **NIST Projects in Additive Manufacturing**



engineering laboratory

#### **Purpose—Test Artifact**

- Two primary methodologies of performance characterization of a machine or process
  - Series of direct measurements of machine or process characteristics
  - Measurement on manufactured test pieces
  - **Direct measurement of AM machines difficult** 
    - Lack of access and control over positioning axes
    - Sensors interfere with process or safety interlocks
- Test pieces play a larger role in AM than in traditional manufacturing



#### **Potential Uses**

- Can demonstrate capabilities and limitations of machine or process
- Can be used as point of comparison
  - Between machines or processes
  - Before and after implementation of improvements
- Can be used as method of performance verification between machine user and vendor

## **Suite of Standards**



laboratory engineering

### **Suite of Standards**

- 1 top level Test Method, 7 process level standard practices (1 for each process category)
- Test Method generally describes
  - potential uses of test artifact
  - test artifact geometry
  - measurements to be taken on the test artifact
  - reporting of results
- Standard Practices provide
  - links to download specific test artifact geometries (different processes may use different size scales)
  - guidance in preparing a build (not a process prescription)
  - specific process parameters to be reported.

## **Prior Work**

- Reviewed more than 40 test artifacts previously described in literature.
- Four categories of test artifacts
  - Comparing different processes
  - Evaluating individual processes
  - Evaluating metal-based processes
  - Other uses

NISTIR 7858, "A Review of Test Artifacts for Additive Manufacturing," May 2012.



## Prior Work → Design Criteria

- The intent of most test artifacts falls into one of two main categories
  - Intended to demonstrate the capabilities of the machine or process
  - Intended to highlight specific machine defects to allow iterative process improvement
  - We seek to design a test artifact that will accomplish both.

## **Design Criteria**

 Test part should demonstrate machine's or process's ability to build features with proper form, orientation, size and location

- Straight features (paraxial and askew)
- Parallel and perpendicular features
- Round features
- Concentric circles or arcs
- Fine features
- Holes and bosses
- Features in planes orthogonal to build plane



## **Design Criteria**

- Design should link specific part defects to specific machine or process errors
  - Geometric errors of beam positioning axes
  - Geometric errors of build platform (z-axis)
  - Alignment errors between axes
  - Beam size

## **Design Criteria**

- General Considerations
  - Easily measurable with low measurement uncertainty
  - Trade off between testing full work volume and the time and material cost. We try to find balance, but side with faster, smaller builds
  - Minimize other variables
    - Support structures
    - Post processing
  - Minimize impact on recoating arm
  - Allow testing of surface roughness along with mechanical and physical properties



## **Description of Proposed Artifact**



![](_page_11_Picture_2.jpeg)

#### **Results—Repeatability**

- Multiple builds by DMLS in stainless steel show average repeatability of approximately 30 μm (2x average standard deviation using several
  - feature measurements)
    - Pin and hole diameters
    - Pin and hole positions
    - Z-heights on staircases
    - Straightness measurements
    - Roundness measurements
    - Flatness measurements

![](_page_12_Figure_9.jpeg)

![](_page_12_Figure_10.jpeg)

#### **Process Improvement**

- Use measured deviations of build 1 to calculate improved beam offset and x- and y-scaling
  - Pins and holes were too close to center; scaling was too small
  - Scaling = slope of best fit line to position deviation of pins and holes (represented as %)
  - Rebuild with adjusted scaling produced pins and holes with position deviations no greater than 52 µm (8 of 10 better than 25 µm)

![](_page_13_Picture_5.jpeg)

![](_page_13_Figure_6.jpeg)

![](_page_13_Figure_7.jpeg)

#### **Questions???**

![](_page_14_Figure_1.jpeg)

#### shawn.moylan@nist.gov

![](_page_14_Picture_3.jpeg)